

Recent Advances in Nanoscale Strain Mapping using 4D STEM

Christoph Gammer

Erich Schmid Institute of Materials Science (ESI),
Austrian Academy of Sciences, Leoben

ÖAW

ÖSTERREICHISCHE
AKADEMIE DER
WISSENSCHAFTEN

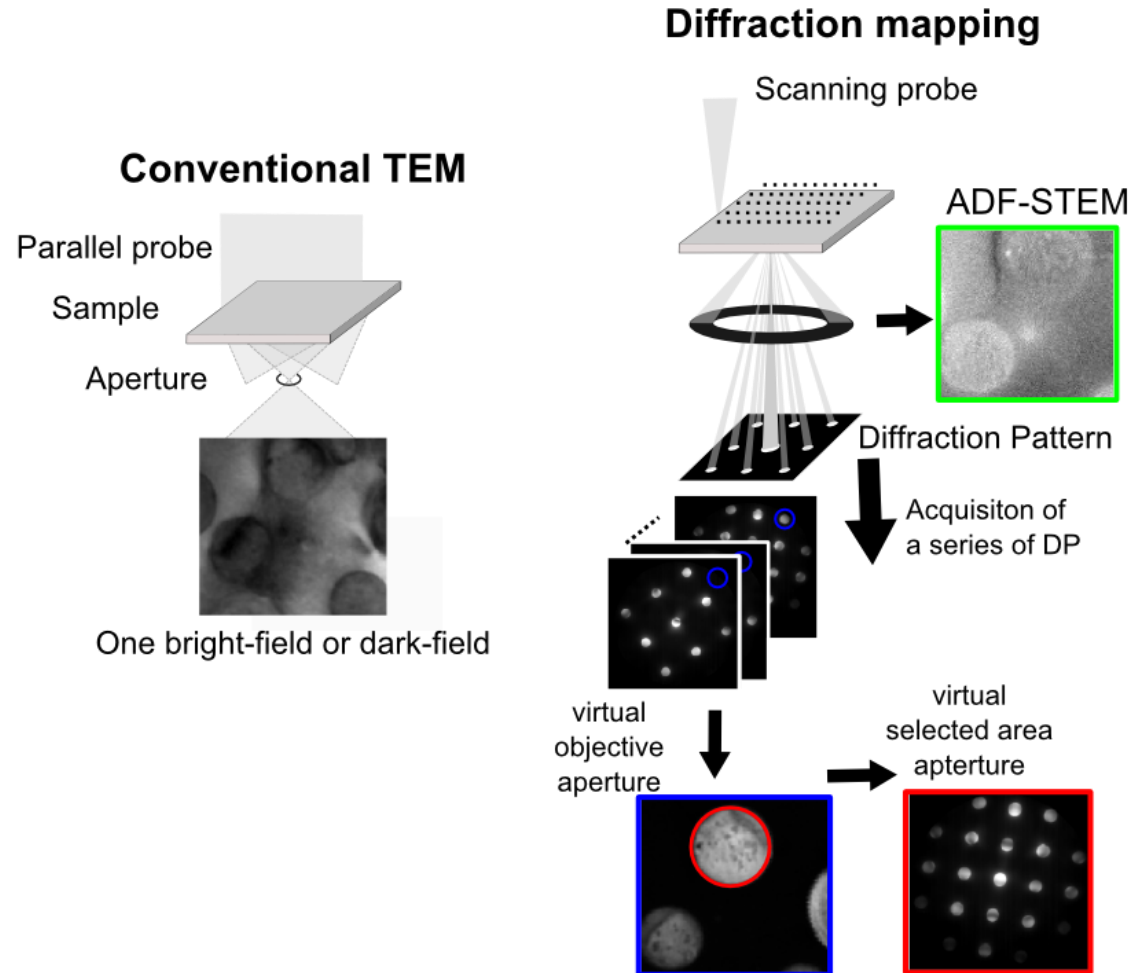


- **4D-STEM**
 - Nanodiffraction strain mapping
- **In situ deformation**
 - Strain mapping during *in situ* deformation
 - Measuring electrical properties during deformation
- **Metallic glasses**
 - Strain mapping in amorphous materials
 - Strain field of a shear band



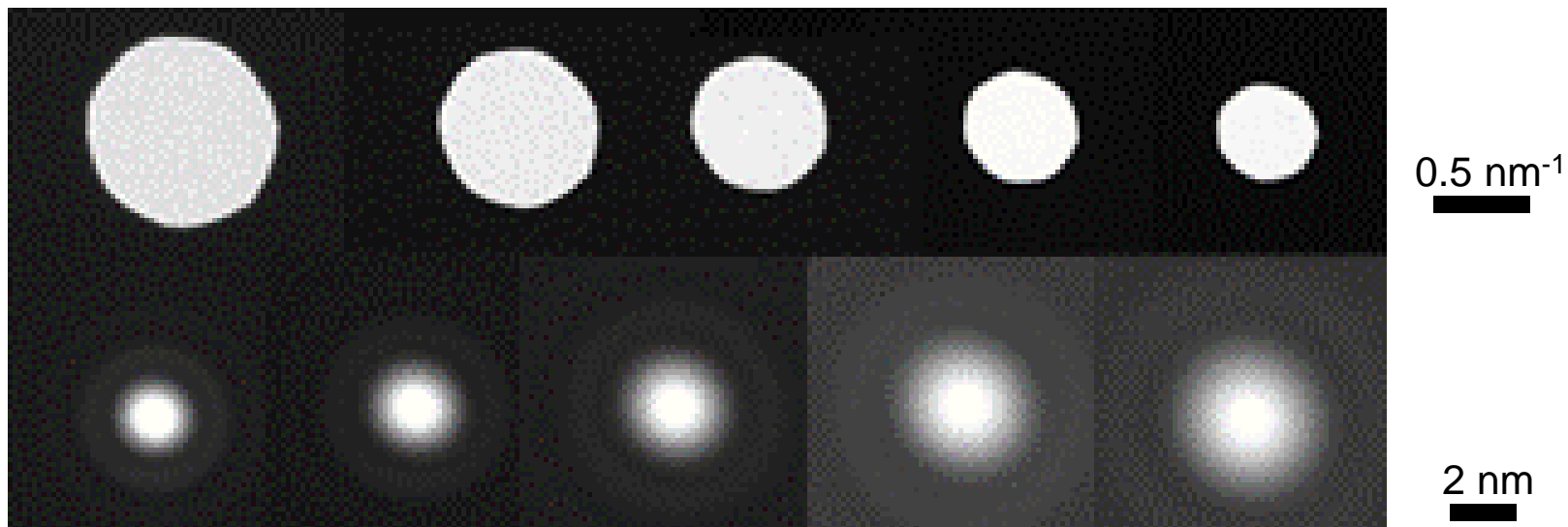
4D-STEM

Experimental setup



Collect maximum available information and extract desired information afterwards

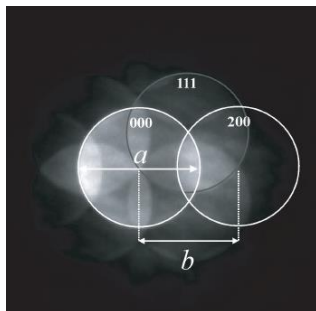
Convergence angle



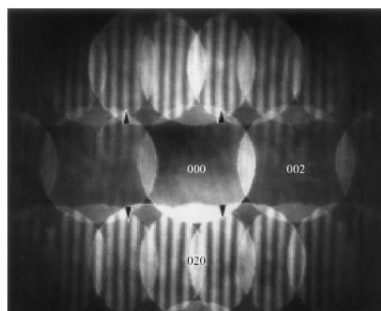
JEOL 2100F

High resolution
Interference

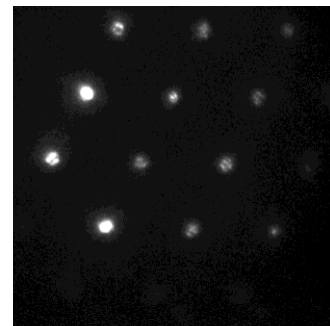
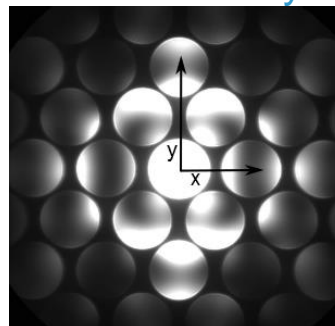
Nanoscale information
Easily detectable



M.Weyland and D.A. Muller.
Tuning the convergence angle for
optimum STEM performance



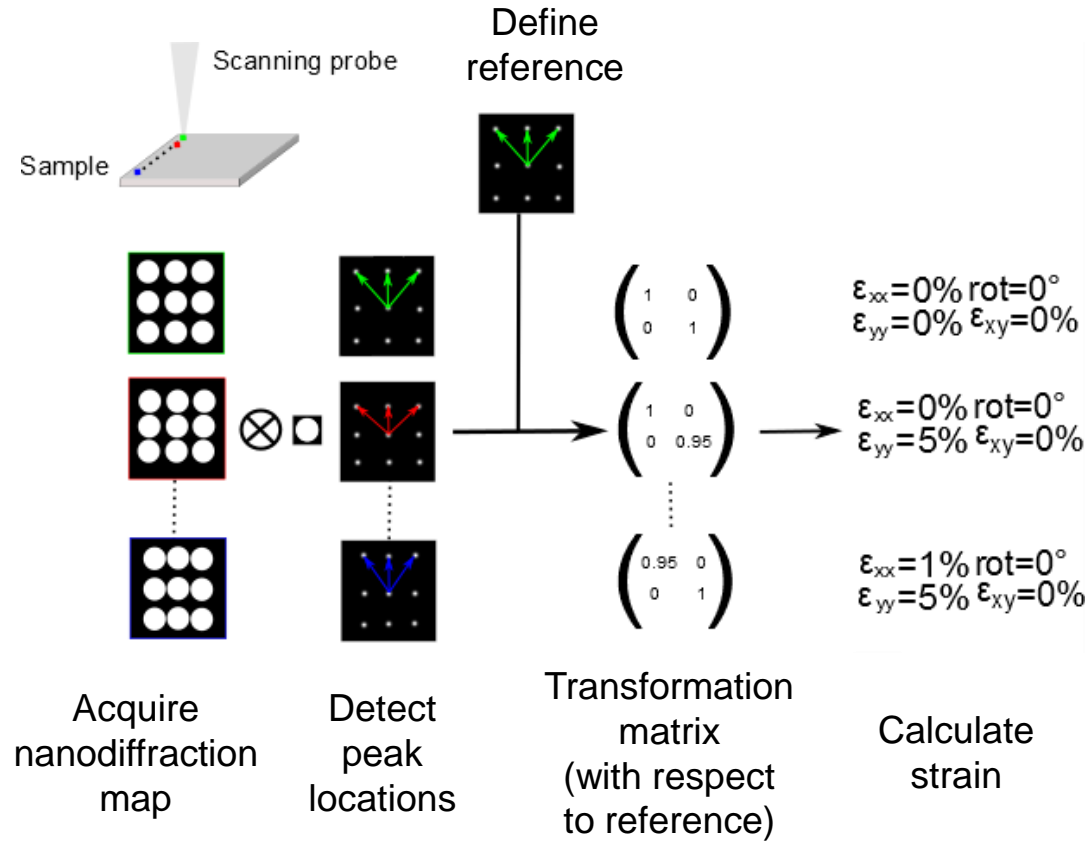
John C H Spence.
Reports on Progress in Physics 69, 3





Nanodiffraction strain mapping

Nanodiffraction strain mapping

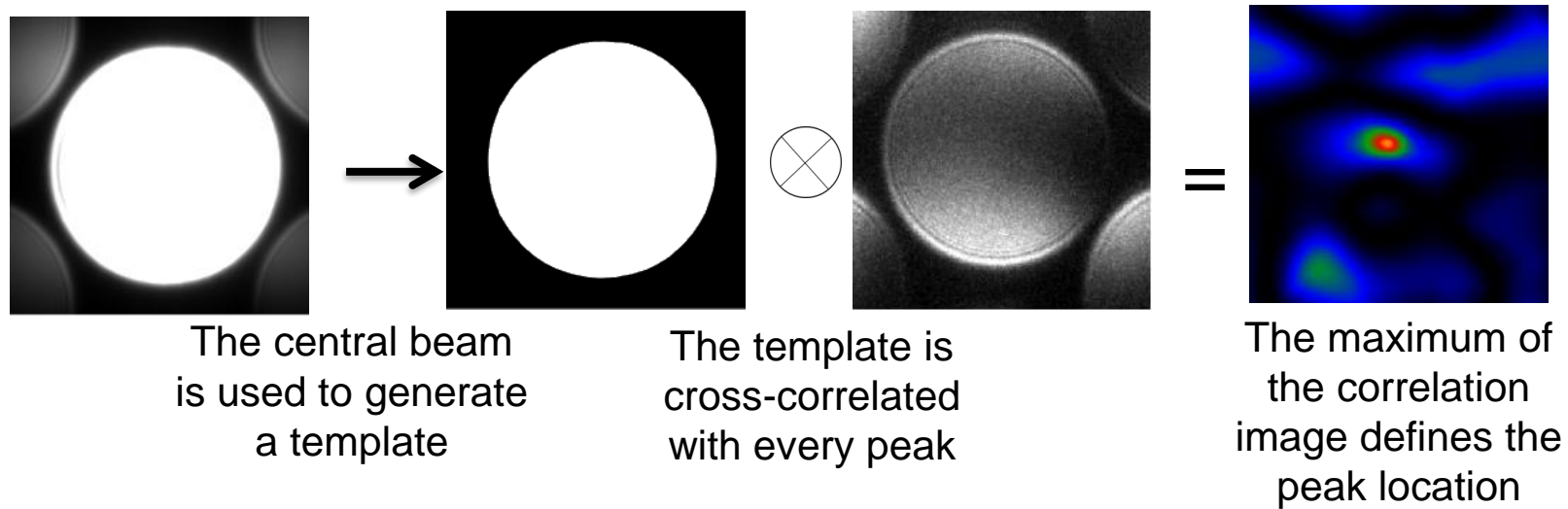


Use all peak positions

correlation value (confidence for peak location) used to weigh peaks

→ **very precise and robust results**

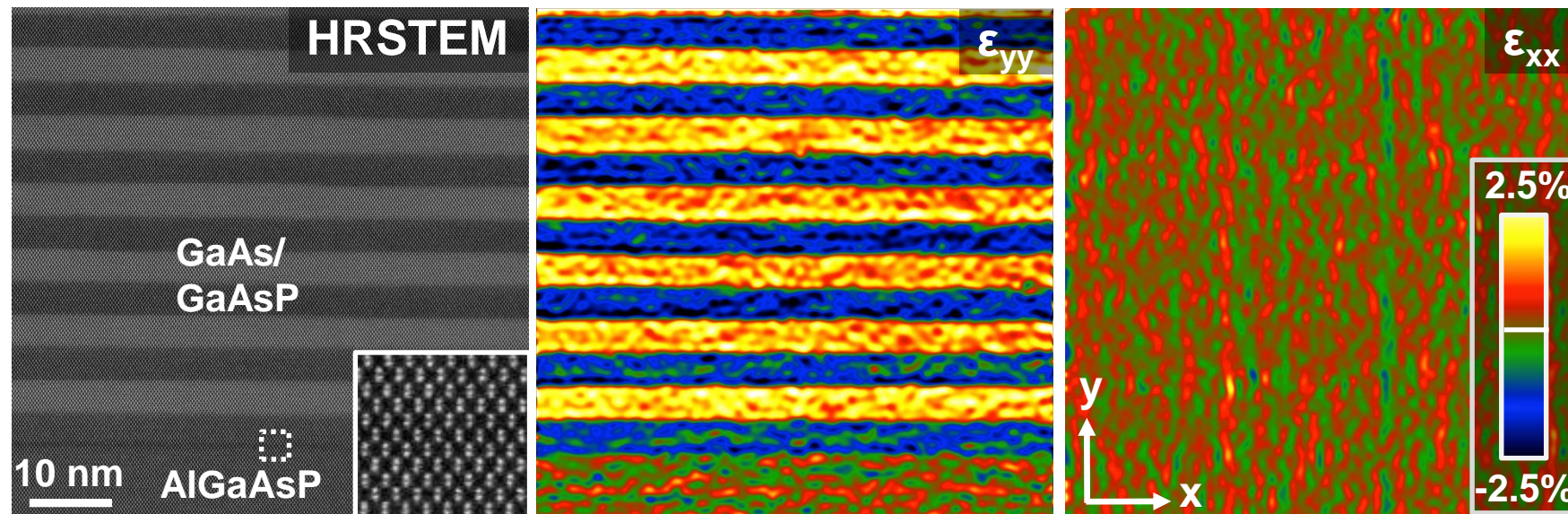
Peak detection



Cross correlation is a fast method to detect the peak position with sub-pixel precision

Atomic resolution STEM

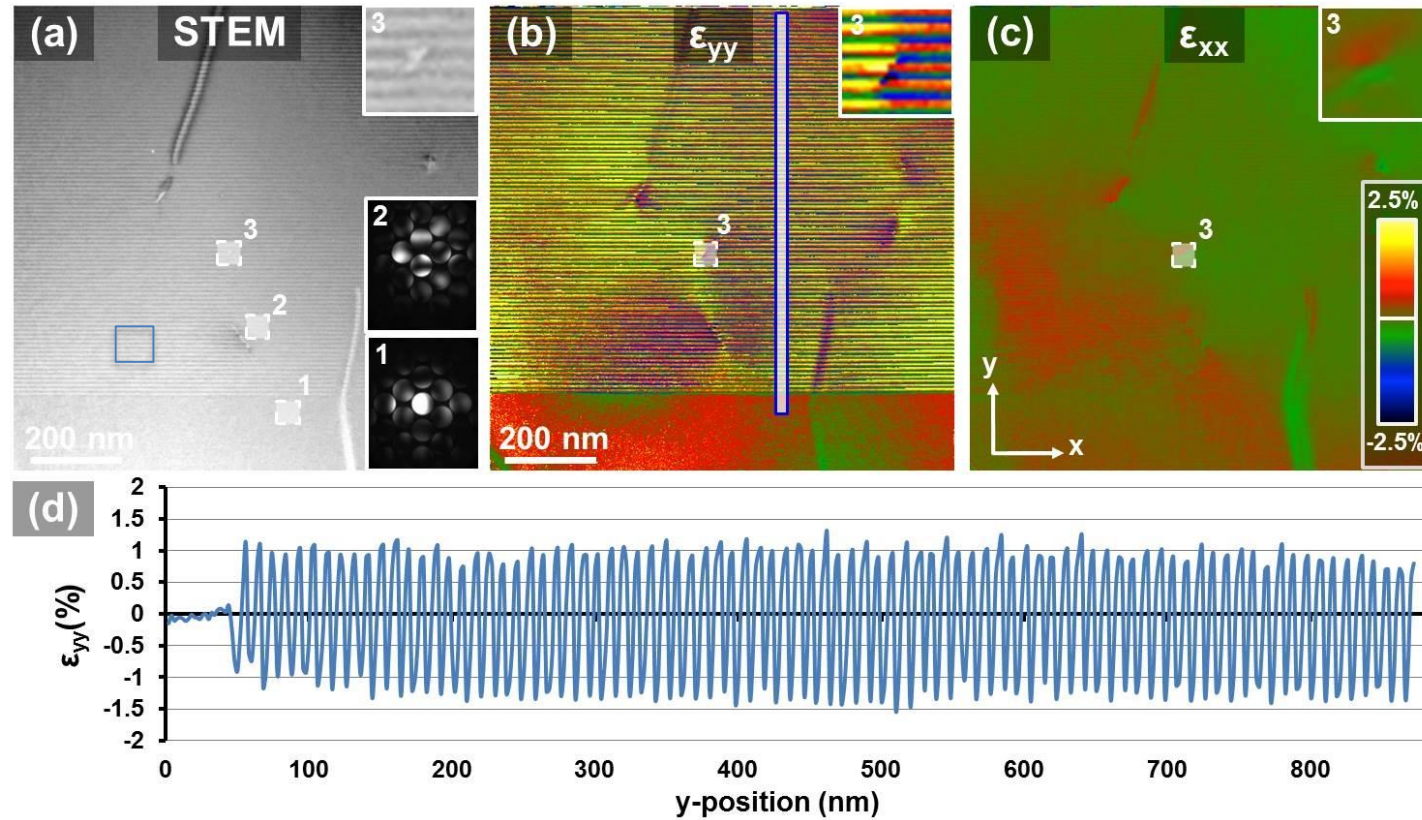
GaAs/GaAsP multilayer



Actual photocathode device consists of 90 pairs of layers (~4 nm)

Large field of view

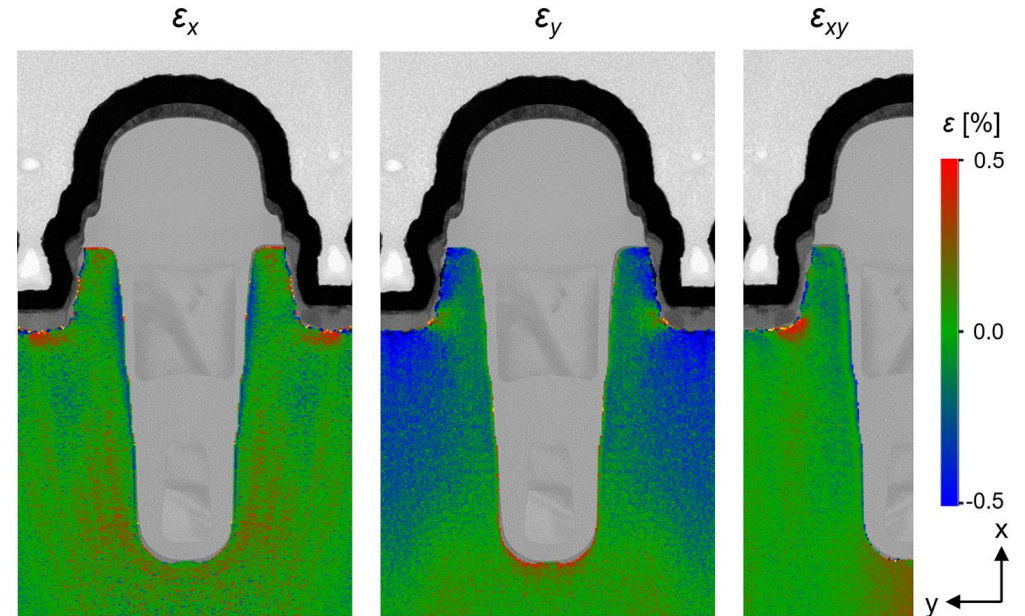
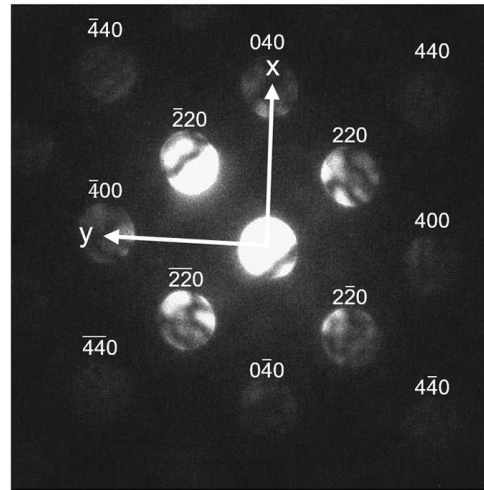
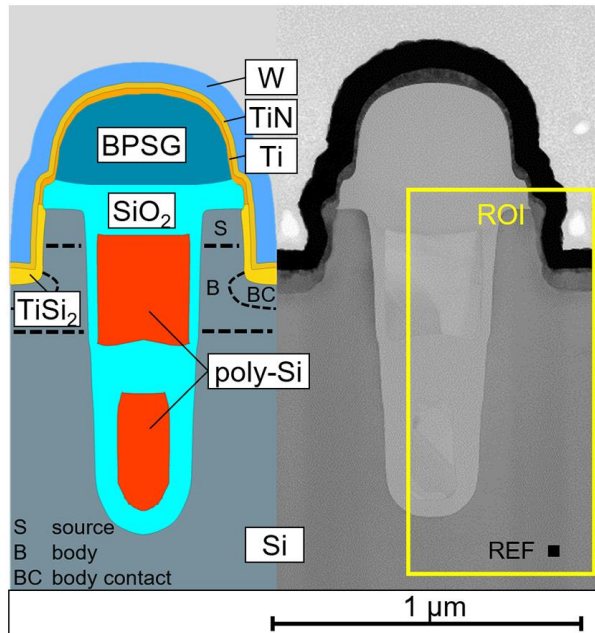
The actual device photocathode device consisting of 90 pairs of layers and contains dislocations, impossible to measure with other techniques.



Diffraction map 512x512 consisting of more than **260,000** diffraction patterns (>1TB data)

Strain map with a field of view $>1\mu\text{m}$ at $<2\text{nm}$ resolution and $<10^{-3}$ precision

Strain in trench power MOSFETs

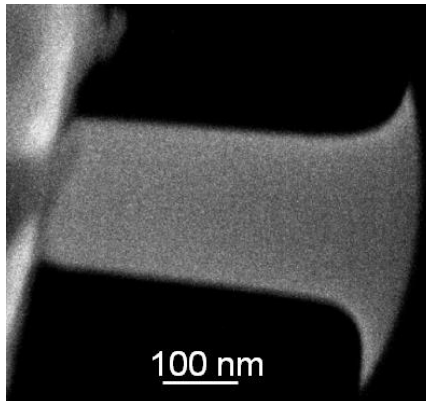


Complex strain fields in actual devices can be measured.

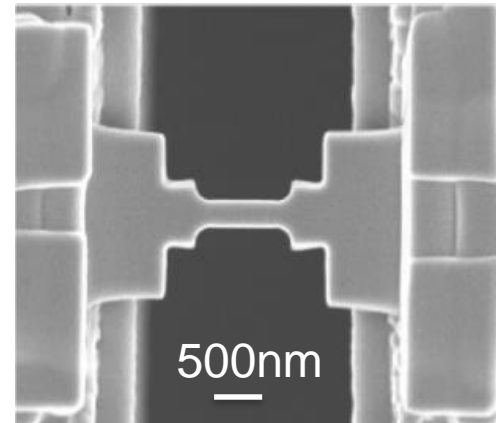


In situ strain mapping

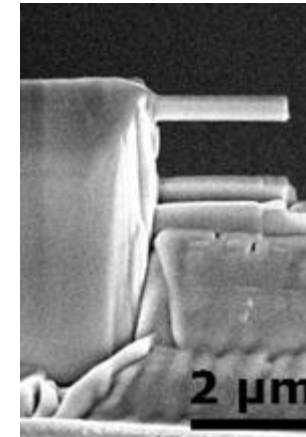
Compression



Tension



Bending

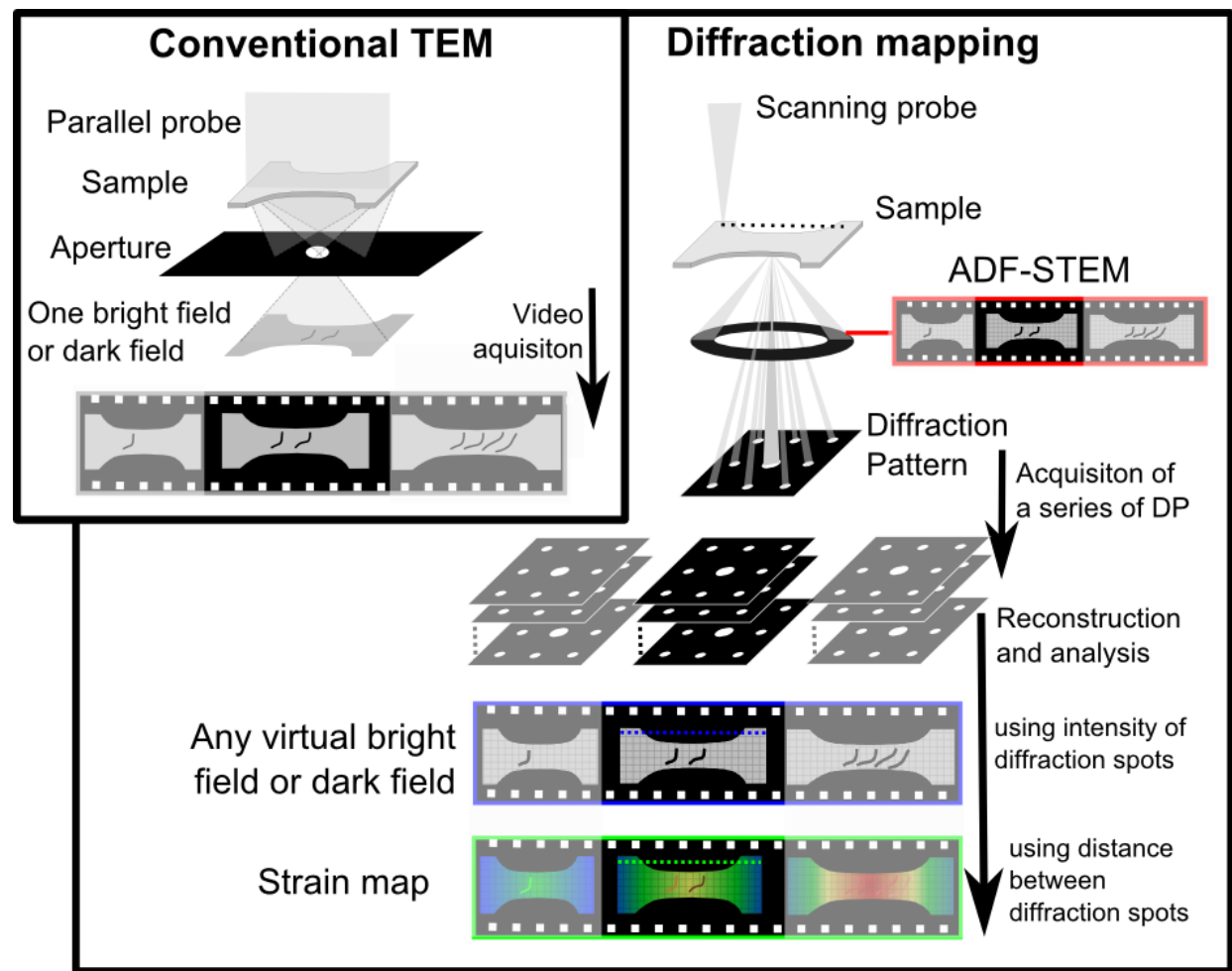


Well defined deformation geometries in combination
with modern deformation holders
→ Quantitative stress strain curves correlated with
real-time videos



Bruker Hysitron PI 95 picoindenter

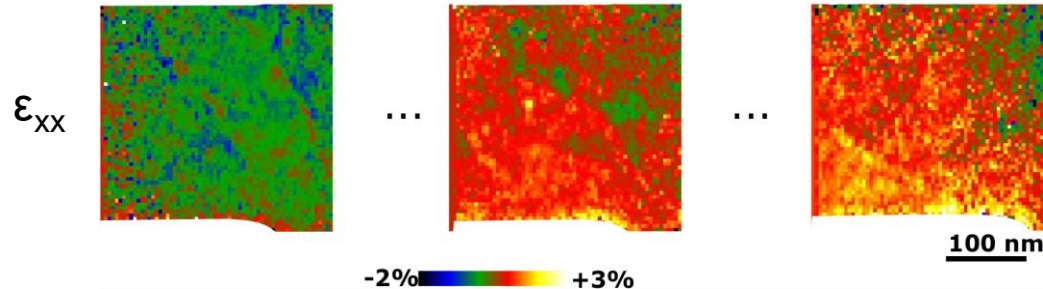
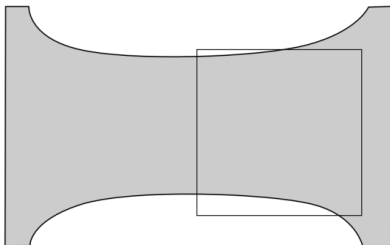
In situ nanodiffraction mapping



A series of diffraction patterns is recorded for every step in time.

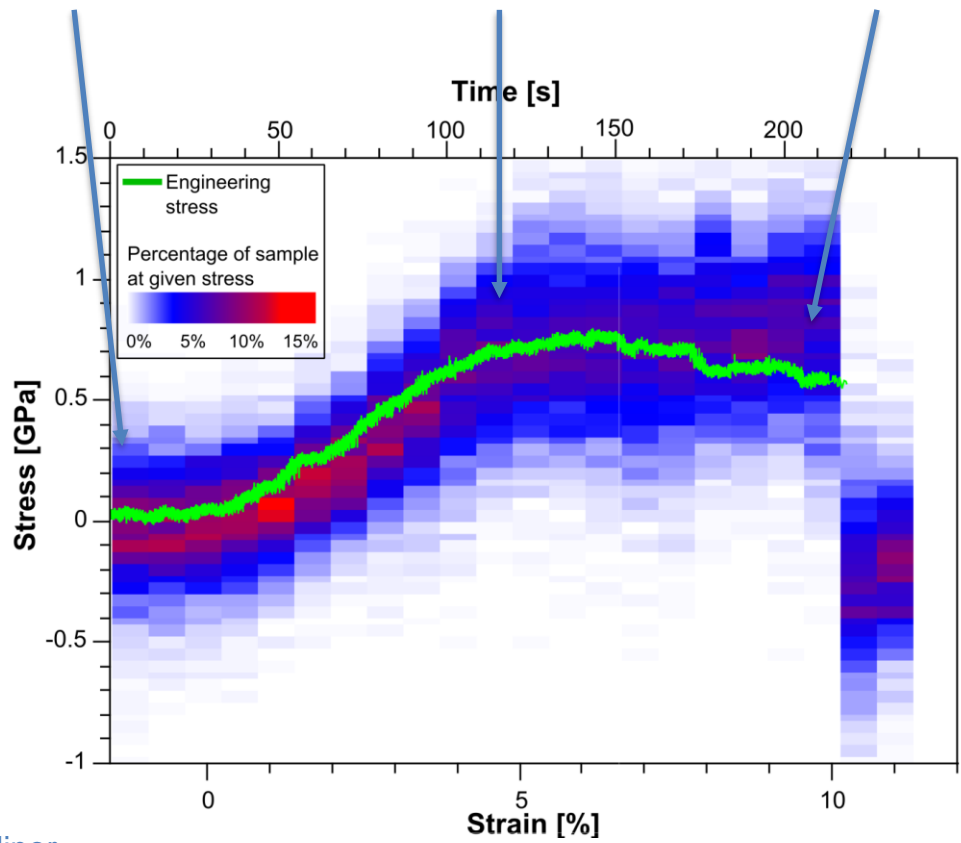
Possible by using ultrafast electron detectors

Local vs. global strain



Local stress histogram
Calculated from
local strains using:
 $\sigma = E \epsilon$
($E=70\text{GPa}$)

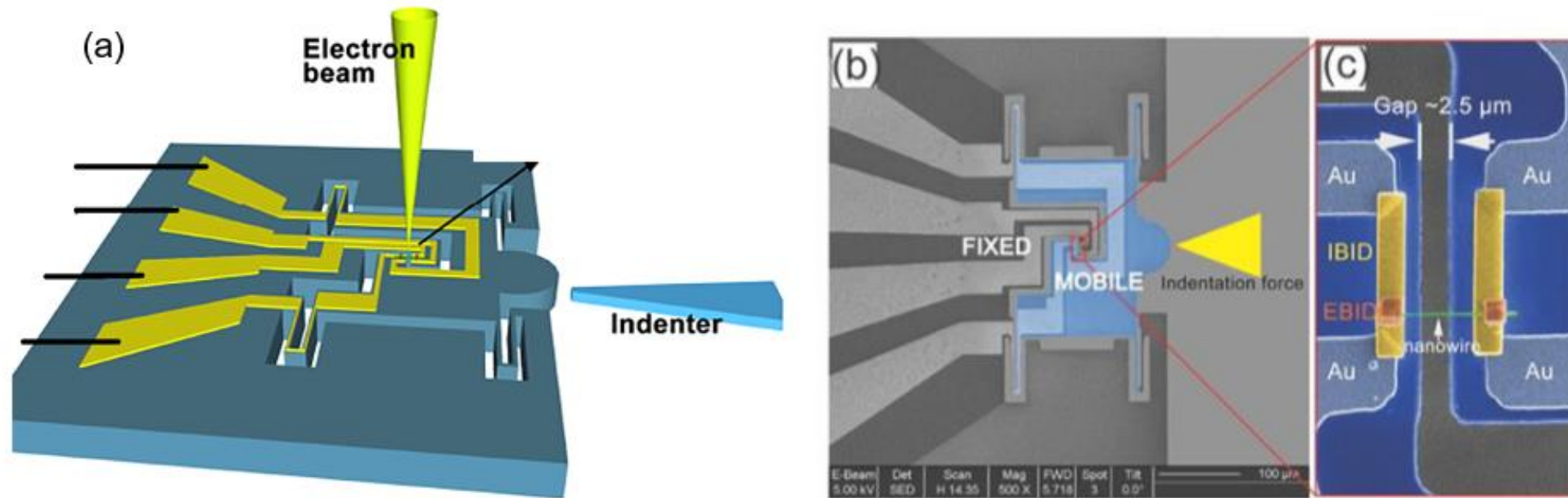
Global stress curve
from indenter





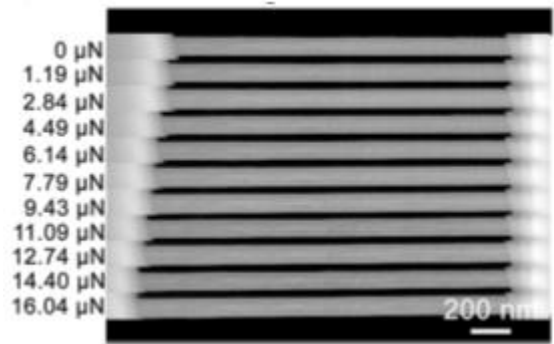
Electrical testing

InAs/In_{0.6}Ga_{0.4}As Core-Shell Nanowires

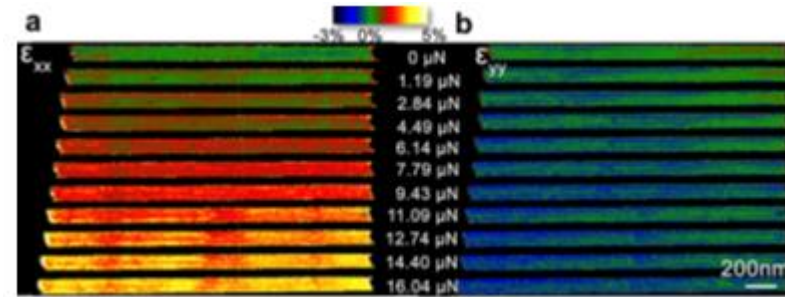


E-PTP device allows to measure electrical properties during deformation

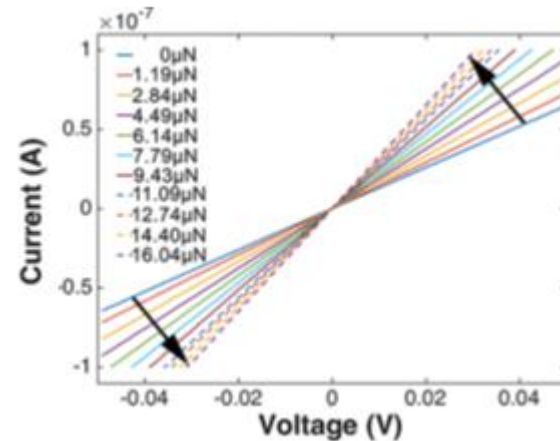
InAs/In_{0.6}Ga_{0.4}As Core-Shell Nanowires



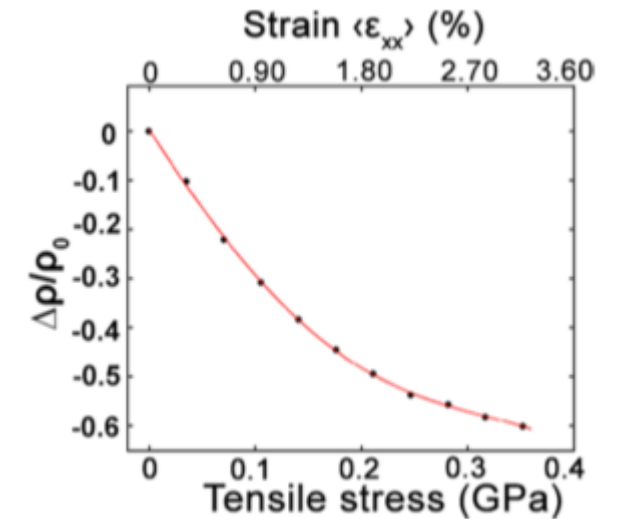
apply load



Measure strain



Measure electrical properties



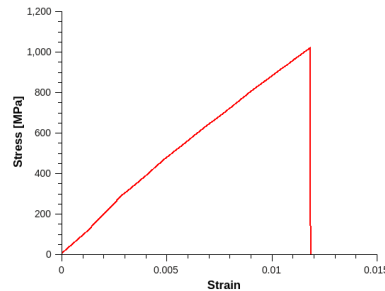
piezoresistance
can be obtained



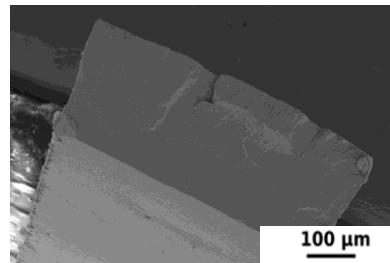
Metallic Glasses

- CuZrAl bulk metallic glass
- High hardness, brittle fracture
- Localized deformation in the form of shear bands

Bulk tensile test

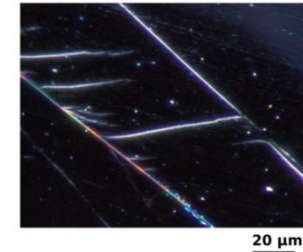
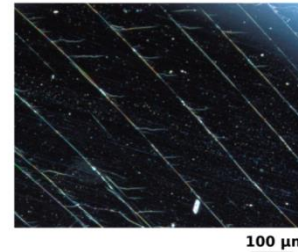


Stress-strain curve



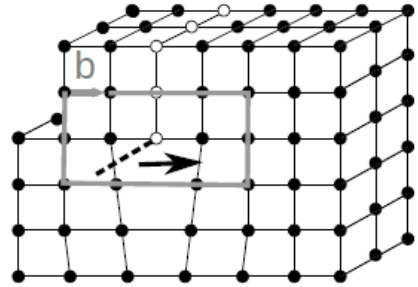
Fracture surface

Rolling (5%)

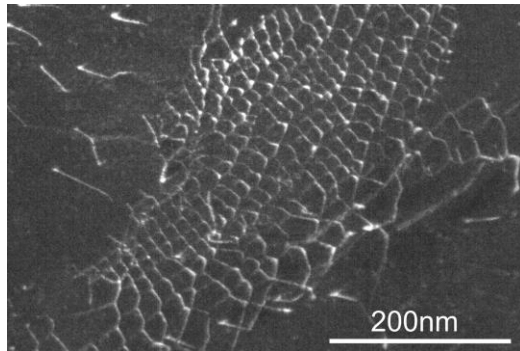


Light microscopic images showing shear bands

Crystalline structure

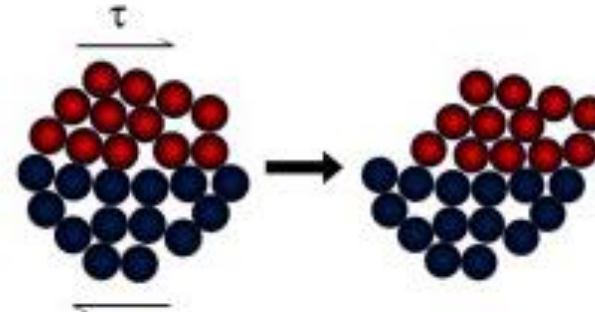


Dislocations



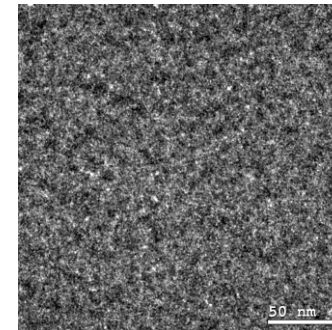
Visible in TEM

Amorphous structure



Shear transformation zone

A. S. Argon, Acta Metall. 27 (1979), 47–58



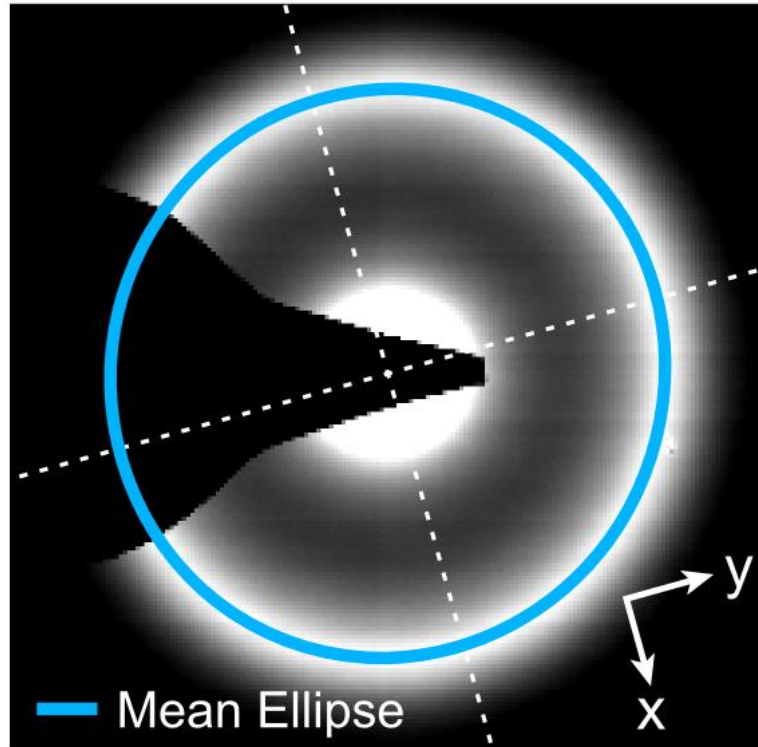
Not visible in TEM,
indications in MD simulations

Formation and propagation of localized deformation not well understood

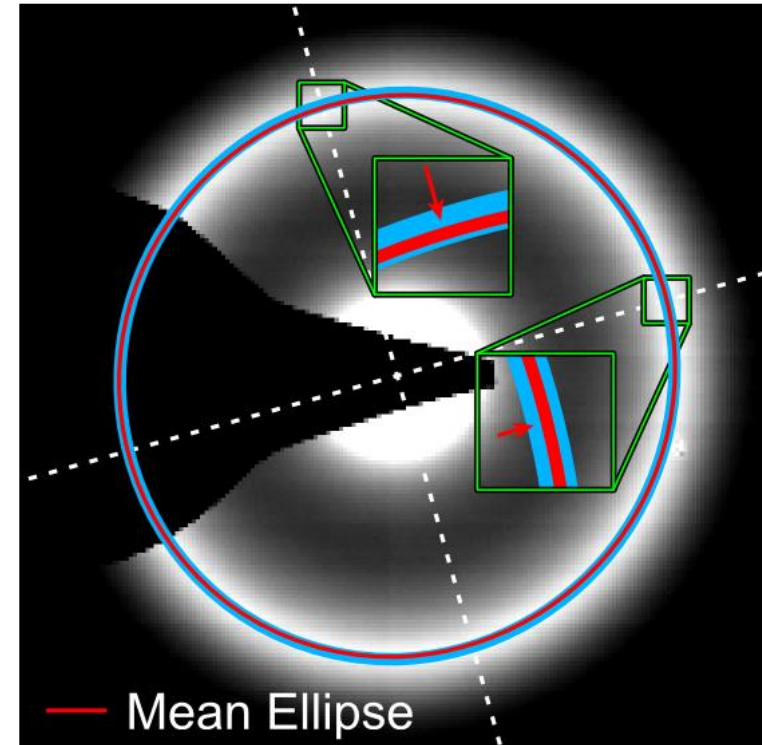
→ TEM at nanometer resolution needed

Strain – elliptic distortion

Unstrained



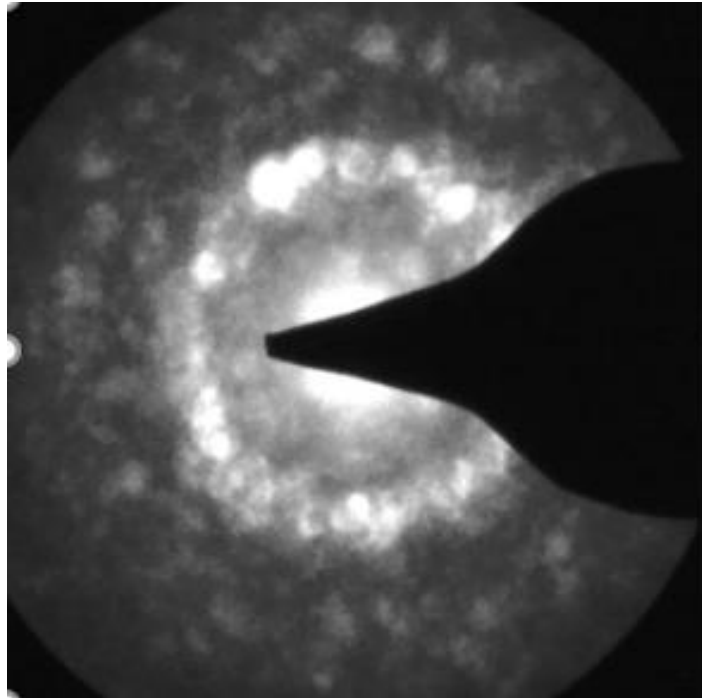
Strained (1%)



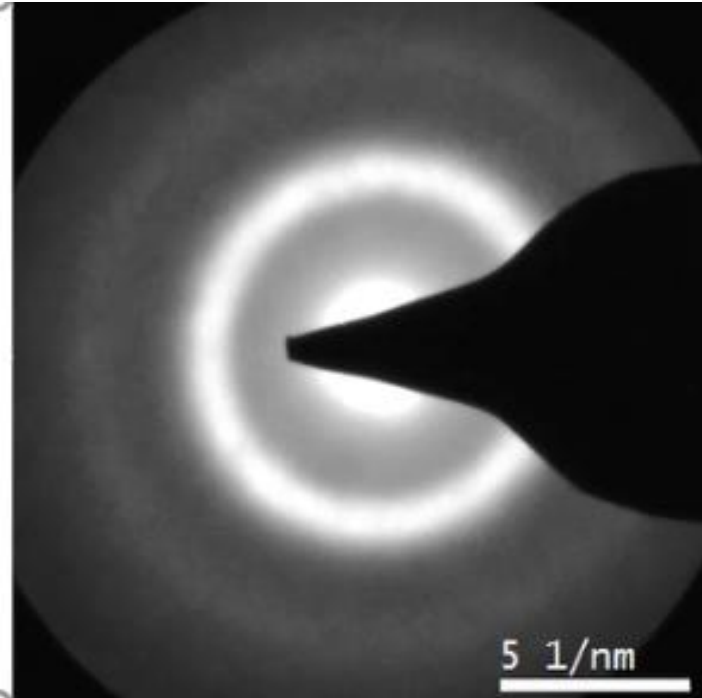
Elastic (atomic) strain

Strain mapping from nanovolumes

Nanodiffraction map



Average of all diffraction patterns

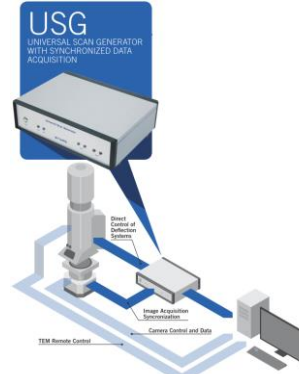


Nanomap transmission electron microscope



www.jeol.de

TEM with in-column energy filter



www.tvips.com

Universal scan generator



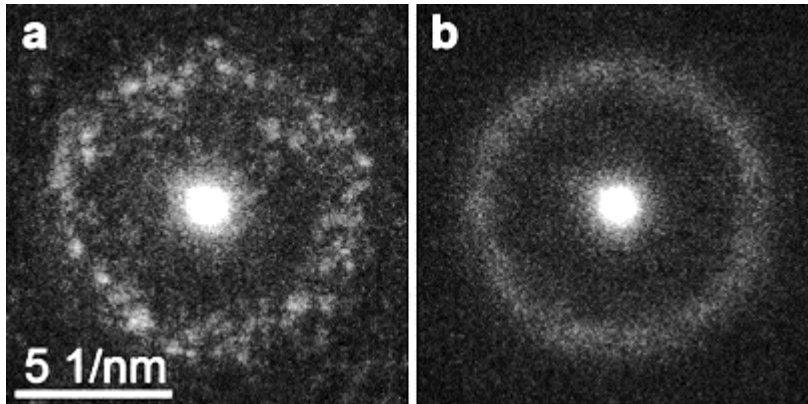
www.tvips.com

High speed CMOS detector (4096x4096 pixel, up to 400fps)



quantumdetectors.com

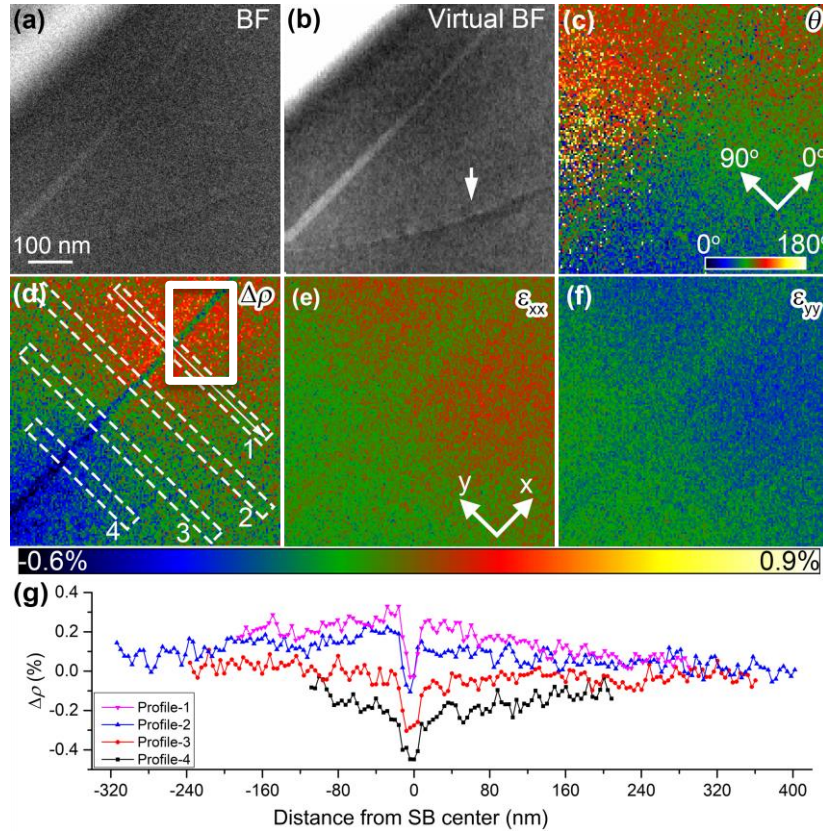
Direct electron detector (512x512pixel, 2kHz/12bit)



Precession:
 < 2 nm resolution
 < 0.1% strain precision

Shear band

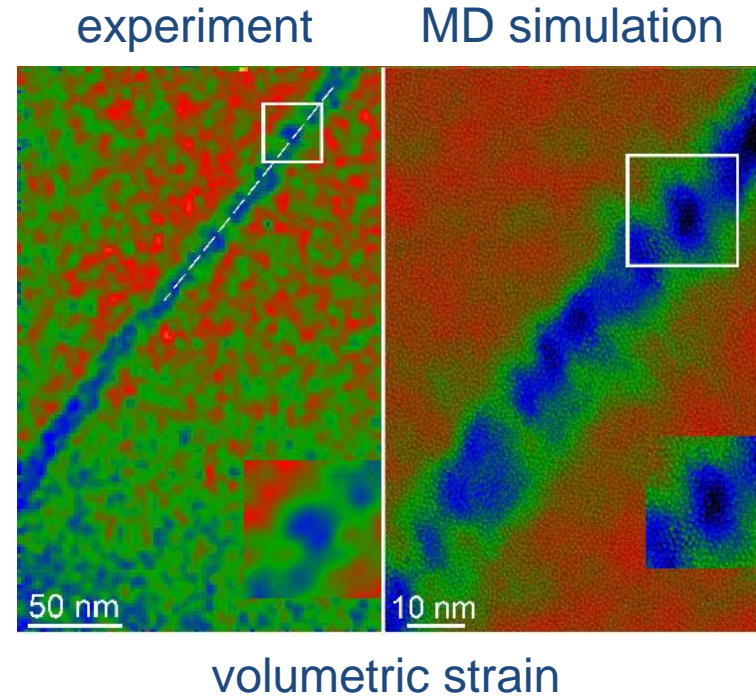
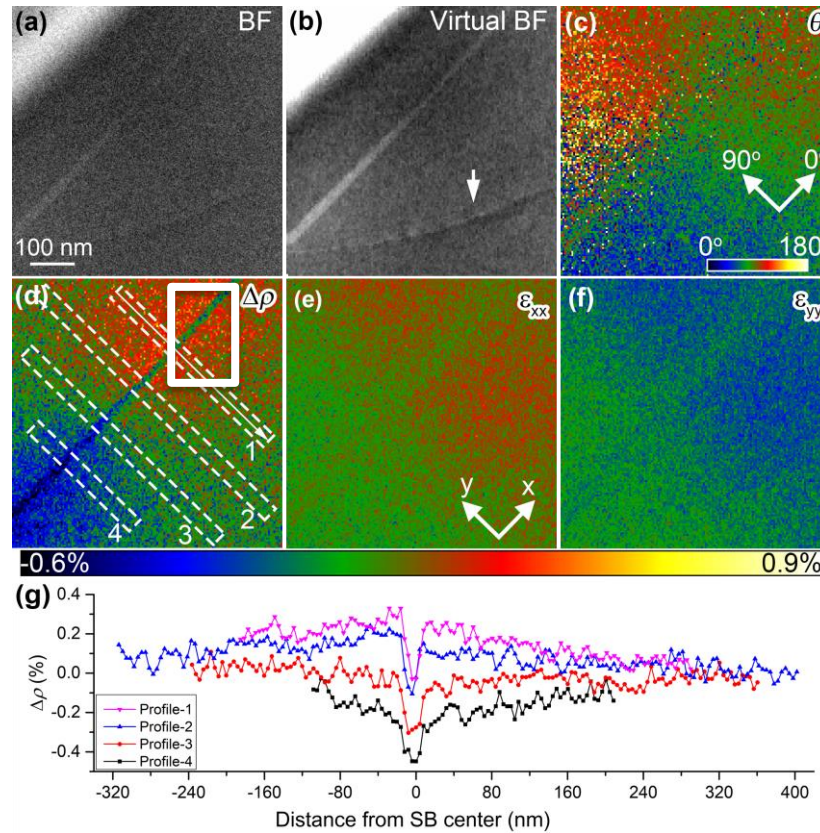
Quantify the elastic strain field (atomic strains) with < 2 nm resolution.



Shear band has lower density

Long-range strains associated with shear band segments

Shear band



Shear band has lower density

Long-range strains associated with shear band segments

Nanoscale density variations can be linked to MD simulations

Strain mapping using 4D-STEM

- Local elastic strain in real devices
- Elastic strain can be measured for crystalline and amorphous materials
- Enables correlation with simulations
- Transient local strain can be measured during in situ experiments
- Recent advances allow to combine electrical and mechanical measurements